

	L #	Hits	Search Text	DBs	Time Stamp
1	L1	2	("20040258930").PN. <i>pre-pub</i>	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB	2006/09/06 12:05
2	L2	0	L1 and "factor of one"	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	2006/09/06 12:06
3	L3	1	L1 and factor	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	2006/09/06 12:06

*Finding support  
for claim 1  
10/602,266*

	L #	Hit s	Search Text	DBs	Time Stamp
1	L1	65	(( "6770515" ) or ( "6927107" ) or ("6607971" ) or ( "6939754" ) or ("6580053" ) or ( "6830965" ) or ("6573163" ) or ( "6495405" ) or ("6686978" ) or ( "6635555" ) or ("6664147" ) or ( "6645454" ) or ("6900083" ) or ( "6809801" ) or ("6733931" ) or ( "7087964" ) or ("6590228" ) or ( "6818484" ) or ("6921434" ) or ( "6903370" ) or ("6727125" ) or ( "6607971" ) or ("6642092" ) or ( "6777276" ) or ("6709910" ) or ( "6913649" ) or ("6765249" ) or ( "7018468" ) or ("6881686" ) or ( "6995053" ) or ("7029961" ) or ( "7056843" )). PN.	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB	2006/09/06 17:29

10/602,266 from Inventor  
Name Search

Day : Wednesday

Date: 9/6/2006

Time: 15:42:24

**PALM INTRANET****Inventor Name Search Result**

Your Search was:

Last Name = MORIGUCHI

First Name = MASAO

Application#	Patent#	Status	Date Filed	Title	Inventor Name
<u>09660516</u>	<u>6770515</u>	150	09/12/2000 ?	SEMICONDUCTOR DEVICE AND METHOD FOR FABRICATING THE DEVICE	MORIGUCHI, MASAO
<u>09667527</u>	<u>6927107</u>	150	09/22/2000 ?	METHOD OF PRODUCING SEMICONDUCTOR DEVICE	MORIGUCHI, MASAO
<u>10136676</u>	<u>6607971</u>	150	04/30/2002 ?	METHOD FOR EXTENDING A LASER ANNEALING PULSE	MORIGUCHI, MASAO
<u>10602266</u>	Not Issued	30	06/23/2003	Grain-free polycrystalline silicon and a method for producing same	MORIGUCHI, MASAO
<u>10640771</u>	<u>6939754</u>	150	08/13/2003 ?	ISOTROPIC POLYCRYSTALLINE SILICON AND METHOD FOR PRODUCING SAME	MORIGUCHI, MASAO
<u>10953938</u>	Not Issued	41	09/28/2004 X	System and method for hydrogen exfoliation	MORIGUCHI, MASAO
<u>11086680</u>	Not Issued	30	03/23/2005 ?	Semiconductor substrate, semiconductor device, and manufacturing methods for them	MORIGUCHI, MASAO
<u>11088252</u>	Not Issued	30	03/24/2005 ?	Semiconductor device, producing method of semiconductor substrate, and producing method of semiconductor device	MORIGUCHI, MASAO
<u>11099198</u>	Not Issued	30	04/04/2005 ?	Isotropic polycrystalline silicon	MORIGUCHI, MASAO
<u>11199166</u>	Not Issued	30	08/09/2005 ?	Method for fabricating semiconductor device and semiconductor device	MORIGUCHI, MASAO

Inventor Search Completed: No Records to Display.

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**PALM INTRANET****Inventor Name Search Result**

Your Search was:

Last Name = VOUTSAS

First Name = APOSTOLOS

Application#	Patent#	Status	Date Filed	Title	Inventor Name
09576939	6432804	150	05/22/2000	SPUTTERED SILICON TARGET FOR FABRICATION OF POLYSILICON THIN FILM TRANSISTORS	VOUTSAS, APOSTOLOS
09576940	6429097	150	05/22/2000	APPARATUS AND METHOD TO SPUTTER SILICON FILMS	VOUTSAS, APOSTOLOS
09653484	6580053	150	08/31/2000	APPARATUS TO CONTROL THE AMOUNT OF OXYGEN INCORPORATED INTO POLYCRYSTALLINE SILICON FILM DURING EXCIMER LASER PROCESSING OF SILICON FILMS	VOUTSAS, APOSTOLOS
09696792	Not Issued	161	10/25/2000	Method of producing a cleaner silicon film	VOUTSAS, APOSTOLOS
09696813	6830965	150	10/25/2000	SEMICONDUCTOR DEVICE AND A METHOD OF CREATING THE SAME UTILIZING METAL INDUCED CRYSTALLIZATION WHILE SUPPRESSING PARTIAL SOLID PHASE CRYSTALLIZATION	VOUTSAS, APOSTOLOS
09774270	Not Issued	164	01/29/2001	MASK PATTERN DESIGN TO IMPROVE QUALITY UNIFORMITY IN LATERAL LASER CRYSTALLIZED POLY-SI FILMS	VOUTSAS, APOSTOLOS
09774290	6573163	150	01/29/2001	METHOD OF OPTIMIZING CHANNEL CHARACTERISTICS USING MULTIPLE MASKS TO FORM LATERALLY CRYSTALLIZED ELA POLY-SI FILMS	VOUTSAS, APOSTOLOS

<u>09774296</u>	6495405	150	01/29/2001	METHOD OF OPTIMIZING CHANNEL CHARACTERISTICS USING LATERALLY-CRYSTALLIZED ELA POLY-SI FILMS	VOUTSAS, APOSTOLOS
<u>09796330</u>	6686978	150	02/28/2001	METHOD OF FORMING AN LCD WITH PREDOMINANTLY <100> POLYCRYSTALLINE SILICON REGIONS	VOUTSAS, APOSTOLOS
<u>09796341</u>	Not Issued	162	02/28/2001	METHOD OF FORMING PREDOMINANTLY <100> POLYCRYSTALLINE SILICON THIN FILM TRANSISTORS	VOUTSAS, APOSTOLOS
<u>09796345</u>	6635555	150	02/28/2001	METHOD OF CONTROLLING CRYSTALLOGRAPHIC ORIENTATION IN LASER-ANNEALED POLYCRYSTALLINE SILICON FILMS	VOUTSAS, APOSTOLOS
<u>09796927</u>	6664147	150	02/28/2001	METHOD OF FORMING THIN FILM TRANSISTORS ON PREDOMINANTLY <100> POLYCRYSTALLINE SILICON FILMS	VOUTSAS, APOSTOLOS
<u>09862092</u>	6649032	150	05/21/2001	SYSTEM AND METHOD FOR SPUTTERING SILICON FILMS USING HYDROGEN GAS MIXTURES	VOUTSAS, APOSTOLOS
<u>09862107</u>	6673220	150	05/21/2001	SYSTEM AND METHOD FOR FABRICATING SILICON TARGETS	VOUTSAS, APOSTOLOS
<u>09881390</u>	6623653	150	06/12/2001	SYSTEM AND METHOD FOR ETCHING ADJOINING LAYERS OF SILICON AND INDIUM TIN OXIDE	VOUTSAS, APOSTOLOS
<u>09893866</u>	Not Issued	163	06/28/2001	Method for forming silicon films with trace impurities	VOUTSAS, APOSTOLOS
<u>09894349</u>	Not Issued	161	06/28/2001	Pulse width method for controlling lateral growth in crystallized silicon films	VOUTSAS, APOSTOLOS
<u>09894940</u>	6645454	150	06/28/2001	SYSTEM AND METHOD FOR REGULATING LATERAL GROWTH IN LASER IRRADIATED SILICON FILMS	VOUTSAS, APOSTOLOS
<u>09906881</u>	6579425	150	07/16/2001	SYSTEM AND METHOD FOR FORMING BASE COAT AND	VOUTSAS, APOSTOLOS

				THIN FILM LAYERS BY SEQUENTIAL SPUTTER DEPOSITING	
09945063	6900083	150	08/31/2001	METHOD OF FORMING MULTI-LAYERS FOR A THIN FILM TRANSISTOR (TFT) AND THE DEVICE FORMED THEREBY	VOUTSAS, APOSTOLOS
10095987	6809801	150	03/11/2002	1:1 PROJECTION SYSTEM AND METHOD FOR LASER IRRADIATING SEMICONDUCTOR FILMS	VOUTSAS, APOSTOLOS
10096293	6660576	150	03/11/2002	SUBSTRATE AND METHOD FOR PRODUCING VARIABLE QUALITY SUBSTRATE MATERIAL	VOUTSAS, APOSTOLOS
10099376	6733931	150	03/13/2002	SYMMETRICAL MASK SYSTEM AND METHOD FOR LASER IRRADIATION	VOUTSAS, APOSTOLOS
10213815	Not Issued	161	08/06/2002	Devices fabricated using apparatus to sputter silicon films	VOUTSAS, APOSTOLOS
10213816	6789499	150	08/06/2002	APPARATUS TO SPUTTER SILICON FILMS	VOUTSAS, APOSTOLOS
10218744	6717178	150	08/13/2002	SEMICONDUCTOR DEVICES FABRICATED USING SPUTTERED SILICON TARGETS	VOUTSAS, APOSTOLOS
10253806	7087964	150	09/23/2002	PREDOMINANTLY <100> POLYCRYSTALLINE SILICON THIN FILM TRANSISTOR	VOUTSAS, APOSTOLOS
10256360	6590228	150	09/26/2002	LCD DEVICE WITH OPTIMIZED CHANNEL CHARACTERISTICS	VOUTSAS, APOSTOLOS
10280990	6818484	150	10/24/2002	METHOD OF FORMING PREDOMINANTLY <100> POLYCRYSTALLINE SILICON THIN FILM TRANSISTORS	VOUTSAS, APOSTOLOS
10345724	Not Issued	161	01/15/2003	Laser annealing apparatus to control the amount of oxygen incorporated into polycrystalline silicon films	VOUTSAS, APOSTOLOS
10384888	Not Issued	71	03/10/2003	Pulse width method for controlling lateral growth in crystallized silicon films	VOUTSAS, APOSTOLOS
10678575	6921434	150	10/03/2003	REGULATED GROWTH METHOD FOR LASER	VOUTSAS, APOSTOLOS

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IRRADIATING SILICON FILMS					
10704928	Not Issued	30	11/10/2003	Silicon film for <u>thin</u> film transistors	VOUTSAS, APOSTOLOS
10705279	6903370	150	11/10/2003	VARIABLE QUALITY SEMICONDUCTOR FILM SUBSTRATE	VOUTSAS, APOSTOLOS
10749060	6878640	150	12/30/2003	METHOD FOR FABRICATING SILICON TARGETS	VOUTSAS, APOSTOLOS
10113144	6792029	150	03/27/2002	METHOD OF SUPPRESSING ENERGY SPIKES OF A PARTIALLY-COHERENT BEAM	VOUTSAS, APOSTOLOS T.
10124826	Not Issued	90	04/17/2002	LASER ANNEALING MASK AND METHOD FOR SMOOTHING AN ANNEALED SURFACE	VOUTSAS, APOSTOLOS T.
10124853	6727125	150	04/17/2002	MULTI-PATTERN SHADOW MASK SYSTEM AND METHOD FOR LASER ANNEALING	VOUTSAS, APOSTOLOS T.
10136676	6607971	150	04/30/2002	METHOD FOR EXTENDING A LASER ANNEALING PULSE	VOUTSAS, APOSTOLOS T.
10194895	6642092	150	07/11/2002	THIN-FILM TRANSISTORS FORMED ON A <u>METAL</u> FOIL SUBSTRATE	VOUTSAS, APOSTOLOS T.
10232089	6777276	150	08/29/2002	SYSTEM AND METHOD FOR OPTIMIZED LASER ANNEALING SMOOTHING MASK	VOUTSAS, APOSTOLOS T.
10273549	6709910	150	10/18/2002	SYSTEM AND METHOD FOR REDUCING SURFACE PROTRUSIONS IN THE FABRICATION OF LILAC SILICON FILMS	VOUTSAS, APOSTOLOS T.
10282744	6911666	150	10/28/2002	FLEXIBLE METAL FOIL SUBSTRATE DISPLAY AND METHOD FOR FORMING SAME	VOUTSAS, APOSTOLOS T.
10602186	6913649	150	06/23/2003	SYSTEM AND METHOD FOR FORMING SINGLE-CRYSTAL DOMAINS USING CRYSTAL SEEDS	VOUTSAS, APOSTOLOS T.
10602266	Not Issued	30	06/23/2003	Grain-free polycrystalline silicon and a method for producing same	VOUTSAS, APOSTOLOS T.

<del>10621845</del>	<del>6765249</del>	150	07/16/2003	THIN-FILM TRANSISTORS FORMED ON A FLEXIBLE SUBSTRATE	VOUTSAS, APOSTOLOS T.
10640771	6939754	150	08/13/2003	ISOTROPIC POLYCRYSTALLINE SILICON AND METHOD FOR PRODUCING SAME	VOUTSAS, APOSTOLOS T.
<del>10655700</del>	Not Issued	<del>161</del>	09/05/2003	Thin-film transistors on a flexible substrate	VOUTSAS, APOSTOLOS T.
10713383	7018468	150	11/13/2003	PROCESS FOR LONG CRYSTAL LATERAL GROWTH IN SILICON FILMS BY UV AND IR PULSE SEQUENCING	VOUTSAS, APOSTOLOS T.
10755487	Not Issued	71	01/12/2004	Thin film structure from LILAC annealing	VOUTSAS, APOSTOLOS T.

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**PALM INTRANET****Inventor Name Search Result**

Your Search was:

Last Name = VOUTSAS

First Name = APOSTOLOS

Application#	Patent#	Status	Date Filed	Title	Inventor Name
10801374	7087537	150	03/15/2004 X	METHOD FOR FABRICATING OXIDE THIN FILMS	VOUTSAS, APOSTOLOS T.
10805120	6881686	150	03/19/2004 P	LOW-FLUENCE IRRADIATION FOR LATERAL CRYSTALLIZATION ENABLED BY A HEATING SOURCE	VOUTSAS, APOSTOLOS T.
10812591	Not Issued	95	03/29/2004 X	HIGH DENSITY PLASMA PROCESS FOR THE FORMATION OF SILICON DIOXIDE ON SILICON CARBIDE SUBSTRATES	VOUTSAS, APOSTOLOS T.
10831424	6995053	150	04/23/2004 ?	VERTICAL THIN FILM TRANSISTOR	VOUTSAS, APOSTOLOS T.
10831443	Not Issued	41	04/23/2004 ?	Multi-pattern shadow mask system for laser annealing	VOUTSAS, APOSTOLOS T.
10831671	Not Issued	83	04/23/2004 ?	Multi-pattern shadow mask laser annealing system	VOUTSAS, APOSTOLOS T.
10862761	Not Issued	71	06/07/2004	Multi-planar layout vertical thin-film transistor inverter	VOUTSAS, APOSTOLOS T.
10871939	Not Issued	41	06/17/2004 X	High density plasma process for silicon thin films	VOUTSAS, APOSTOLOS T.
10883381	7046715	150	07/01/2004 X	METHOD FOR SUPPRESSING ENERGY SPIKES OF A PARTIALLY-COHERENT BEAM USING TRIANGULAR END-REGIONS	VOUTSAS, APOSTOLOS T.
10897763	6959029	150	07/22/2004 P	APPARATUS FOR PERFORMING ANASTOMOSIS	VOUTSAS, APOSTOLOS T.
10913678	7029961	150	08/05/2004	METHOD FOR OPTIMIZED LASER ANNEALING SMOOTHING	VOUTSAS, APOSTOLOS T.

<del>10953913</del>	Not Issued	161	09/28/2004	Dual-gate thin-film transistor	VOUTSAS, APOSTOLOS T.
<del>10985587</del>	Not Issued	30	11/09/2004	Simultaneous planar and non-planar thin-film transistor processes	VOUTSAS, APOSTOLOS T.
<del>11013605</del>	Not Issued	30	12/15/2004	High-density plasma hydrogenation	VOUTSAS, APOSTOLOS T.
<del>11031316</del>	Not Issued	30	01/05/2005	Method for forming a flexible metal foil substrate display	VOUTSAS, APOSTOLOS T.
<del>11062068</del>	<del>7056843</del>	<del>150</del>	02/18/2005	LOW-FLUENCE IRRADIATION FOR LATERAL CRYSTALLIZATION ENABLED BY A HEATING SOURCE	VOUTSAS, APOSTOLOS T.
<del>11099198</del>	Not Issued	30	04/04/2005	Isotropic polycrystalline silicon	VOUTSAS, APOSTOLOS T.
<del>11101741</del>	Not Issued	30	04/07/2005	Structures with seeded single-crystal domains	VOUTSAS, APOSTOLOS T.
<del>11139726</del>	Not Issued	30	05/26/2005	High-density plasma oxidation for enhanced gate oxide performance	VOUTSAS, APOSTOLOS T.
<del>11184699</del>	Not Issued	20	07/18/2005	Dual-gate transistor display	VOUTSAS, APOSTOLOS T.
<del>11218111</del>	Not Issued	30	09/01/2005	High density plasma grown silicon nitride	VOUTSAS, APOSTOLOS T.
<del>11261194</del>	Not Issued	30	10/28/2005	Thin-film transistor with vertical channel region	VOUTSAS, APOSTOLOS T.
<del>11263604</del>	Not Issued	20	10/31/2005	Pulse sequencing lateral growth method	VOUTSAS, APOSTOLOS T.
<del>11264979</del>	Not Issued	30	11/02/2005	High-density plasma multilayer gate oxide	VOUTSAS, APOSTOLOS T.
<del>11327612</del>	Not Issued	30	01/06/2006	Enhanced thin-film oxidation process	VOUTSAS, APOSTOLOS T.
<del>11387626</del>	Not Issued	20	03/23/2006	Two-transistor tri-state inverter	VOUTSAS, APOSTOLOS T.
<del>11408220</del>	Not Issued	30	04/20/2006	Four-transistor Schmitt trigger inverter	VOUTSAS, APOSTOLOS T.
<del>11418273</del>	Not Issued	30	05/04/2006	Silicon oxide thin-films with embedded nanocrystalline silicon	VOUTSAS, APOSTOLOS T.
<del>11439410</del>	Not Issued	20	05/23/2006	Digital-to-time converter	VOUTSAS, APOSTOLOS T.
<del>11479221</del>	Not Issued	30	06/30/2006	Sidewall gate thin-film transistor	VOUTSAS, APOSTOLOS T.

<u>08928600</u>	<u>5994156</u>	150	09/12/1997	<input checked="" type="checkbox"/> <input type="checkbox"/>	METHOD OF MAKING GATE AND SOURCE LINES IN TFT LCD PANELS USING PURE ALUMINUM METAL	VOUTSAS, APOSTOLOS T.
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Inventor Search Completed: No Records to Display.

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